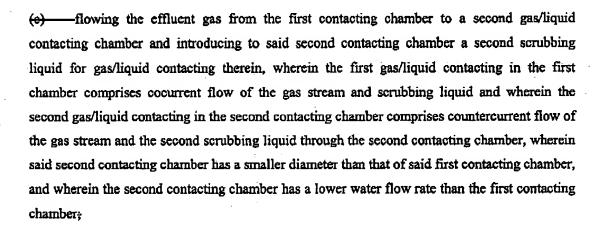


1-20 (Previously cancelled)

- 21. (Currently amended) A scrubbing process for the abatement of a gas component in a gas stream containing same, said scrubbing process comprising introducing the gas stream and a scrubbing liquid to a first gas/liquid contacting chamber and effecting gas/liquid contacting therein, wherein said process additionally comprises at least one of the steps of:
- introducing a chemical reagent for contact with the gas component to remove same from the gas stream in said gas/liquid contacting;
- introducing to the gas stream prior to entry thereof into the contacting chamber, a gas to enhance removal of silane from the gas stream when present therein;



- introducing an antifoam agent to scrubbing liquid for said gas/liquid contacting, to suppress foam production in the contacting chamber;
- suppressing deposition of calcium carbonate from scrubbing liquid containing calcium, including a step selected from the group consisting of:
 - imposing a magnetic field on scrubbing liquid prior to use thereof in the contacting chamber:
 - -adjusting the pH of the scrubbing liquid to maintain pH thereof below 8.5;



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- (3) flowing the sarubbing liquid through a lime sode ash bed prior to use of the sarubbing liquid in the contacting chamber; and
- (4) precipitating the calcium content of the corubbing liquid prior to use of the corubbing liquid in the contacting chamber; and

(f)—suppressing solids formation in a passage of the scrubbing system, said passage comprising a conduit to a pressure sensing device, including a step selected from the group consisting of flowing a purge gas through the passage to suppress solids formation therein, and heating the passage to suppress solids formation therein.

22-25. (Previously cancelled)

26. (Previously presented) A scrubbing process for treatment of an effluent gas including acid gas components and water-scrubbable components other than acid gas component, said process comprising:

scrubbing the effluent gas with a neutral aqueous scrubbing liquid in a first scrubbing zone to remove the acid gas components of the effluent gas, with co-current flow contacting of the aqueous scrubbing liquid and effluent gas with one another to yield effluent gas reduced in acid gas components;

flowing the effluent gas reduced in acid gas components from the first scrubber unit to a second scrubber unit; and

scrubbing the effluent gas with a second aqueous scrubbing liquid in the second scrubbing zone to remove water-scrubbable components other than acid gas component from the effluent gas, with counter-current flow contacting of the second aqueous scrubbing liquid and effluent gas with one another to yield effluent gas reduced in acid gas components and water-scrubbable components other than acid gas components, wherein said second scrubbing zone has a smaller diameter than that of said first scrubbing zone, and wherein the second scrubbing zone has a lower water flow rate than the first scrubbing zone chamber.

27. (Previously presented) The process according to claim 26, wherein the first scrubbing zone is a vessel enclosing an interior volume containing a bed of packing medium.



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28-50. (Previously cancelled)

- 51. (Previously presented) The process according to claim 26 wherein the scrubbing liquid in the second scrubbing zone contains no chemical injection agent.
- 52. (Previously presented) The process according to claim 21 wherein the scrubbing liquid in the first contacting chamber and second chamber is water.
- 53. (Previously presented) The process according to claim 21 wherein the first scrubbing liquid contains no chemical injection agent.
- 54. (Previously presented) The process according to claim 21 wherein the second scrubbing liquid contains no chemical injection agent.

55-56. (Previously cancelled)

- 57. (Previously presented) The process according to claim 21 wherein the diameter of the second contacting chamber is about 0.20 the diameter of the first contacting chamber.
- 58. (Previously presented) The process according to claim 26 wherein the diameter of the second scrubbing zone is about 0.20 the diameter of the first scrubbing zone.

59-60. (Previously cancelled)

61. (Currently amended) A scrubbing process for the abatement of a gas component in a gas stream containing same, said scrubbing process comprising:

introducing the gas stream and a scrubbing liquid to a first gas/liquid contacting chamber and effecting gas/liquid contacting therein; flowing the effluent gas from the first contacting chamber to a second gas/liquid contacting chamber and introducing to said second contacting chamber a second scrubbing liquid for gas/liquid contacting therein, wherein the first gas/liquid contacting in the first chamber comprises co-current flow of the gas stream and scrubbing liquid, and wherein the second gas/liquid contacting in the second contacting chamber



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comprises countercurrent flow of the gas stream and the second scrubbing liquid through the second contacting chamber, wherein said second contacting chamber has a smaller diameter than that of said first contacting chamber, and wherein the second contacting chamber has a lower water flow rate than the first contacting chamber, and wherein the second scrubbing liquid is not recirculated.



62-64. (Previously cancelled)